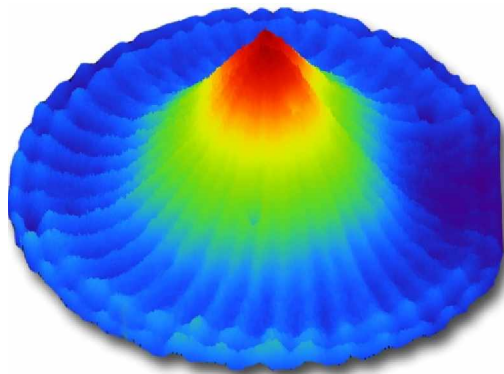
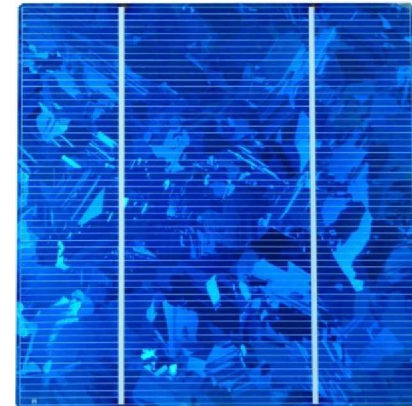


Measuring Examples:
Measurements on Solar Cells & Wafers
with Precitec Sensors

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63110 Rodgau (Germany)
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Tel.: +49 / 6106 / 8290-0
www.Precitec-Optronik.de

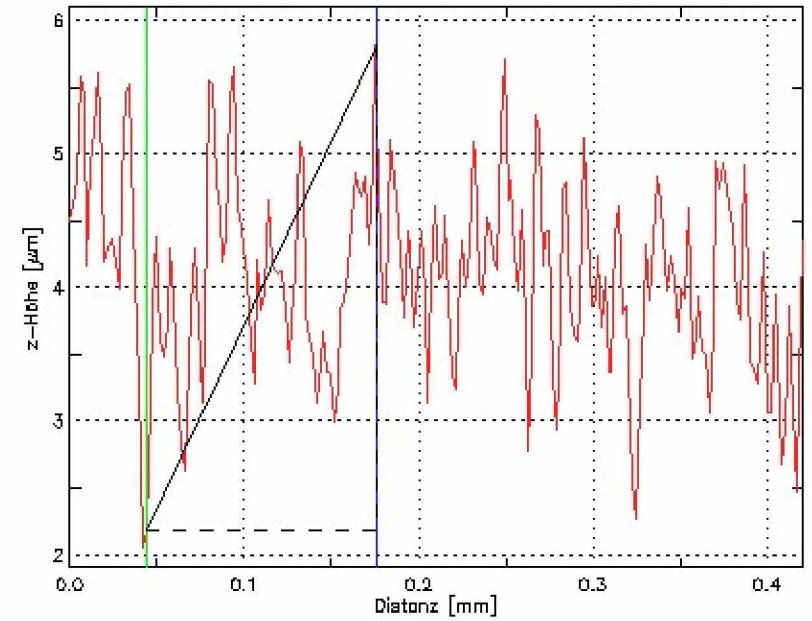
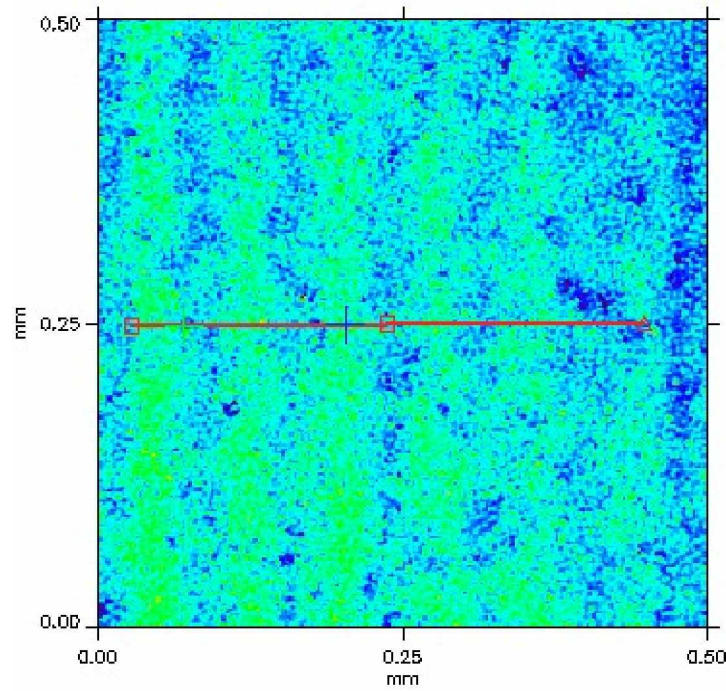


Ideas with system



Measuring Examples

CHRcodile E: Wafer Topography

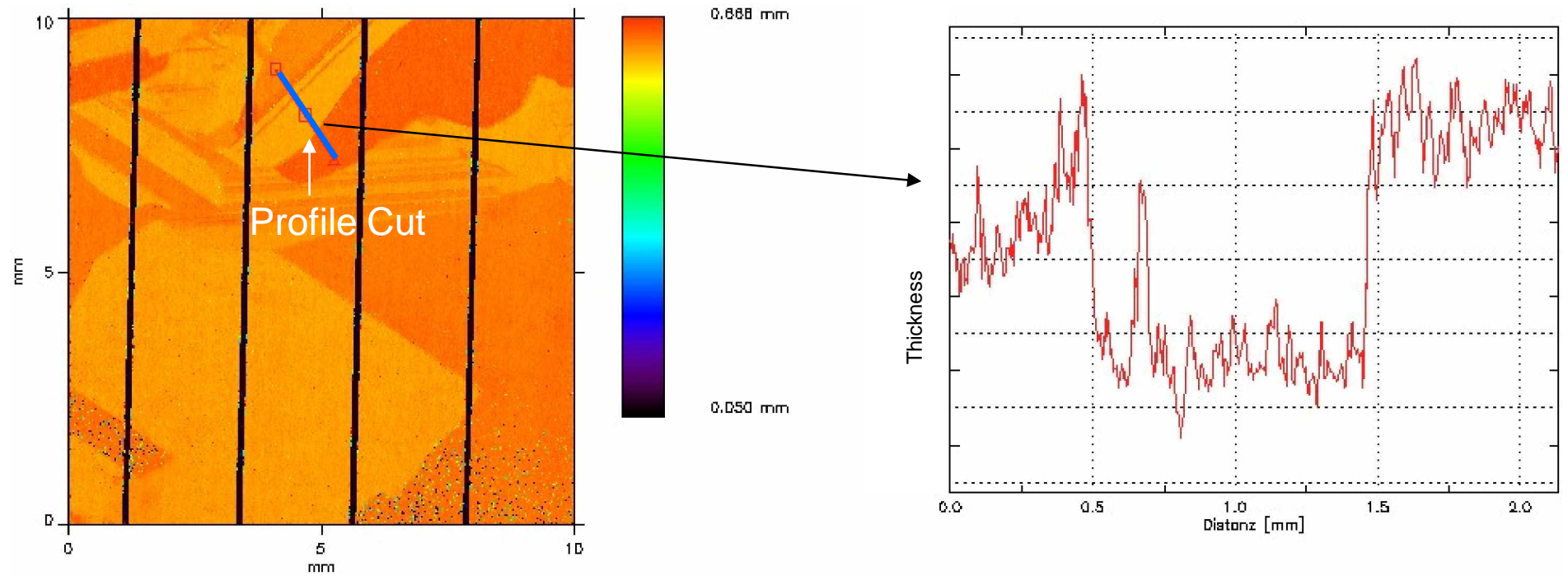


Ideas with system



Measuring Examples

CHRcodile IT: Thickness Scan on Solar Cell

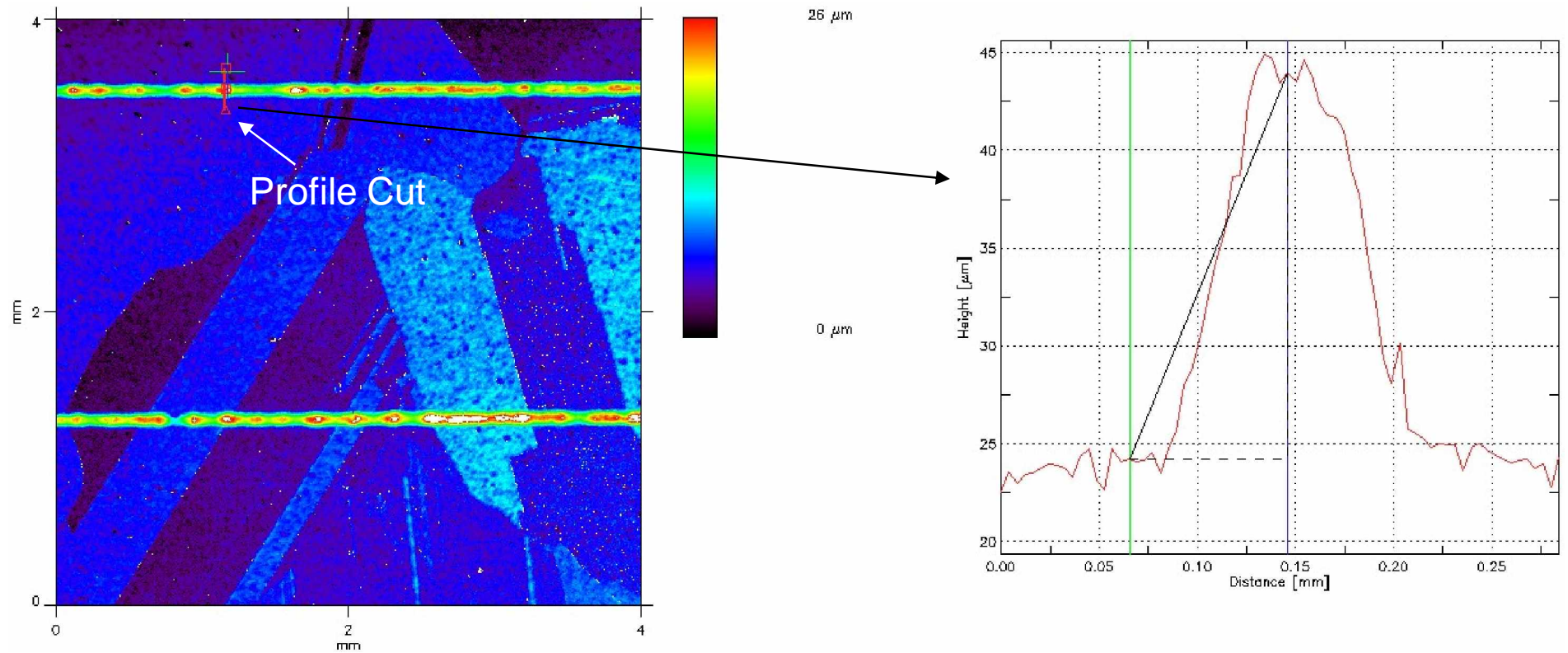


Ideas with system



Measuring Examples

CHRcodile E: Height of a Printed Finger on Solar Cell

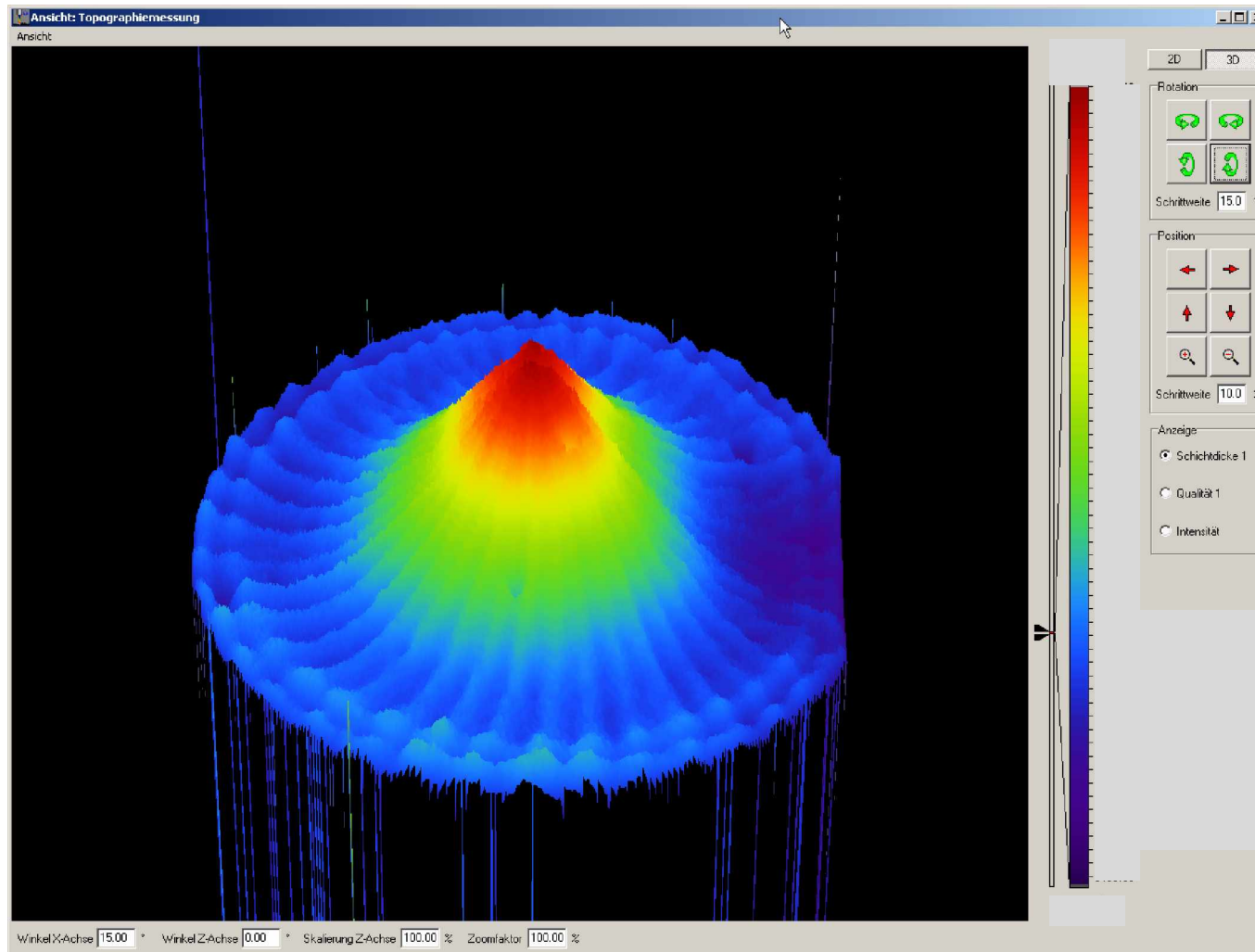


Ideas with system



Measuring Examples

CHRcodile IT: Thickness Scan of a Si-Wafer – 3D Picture

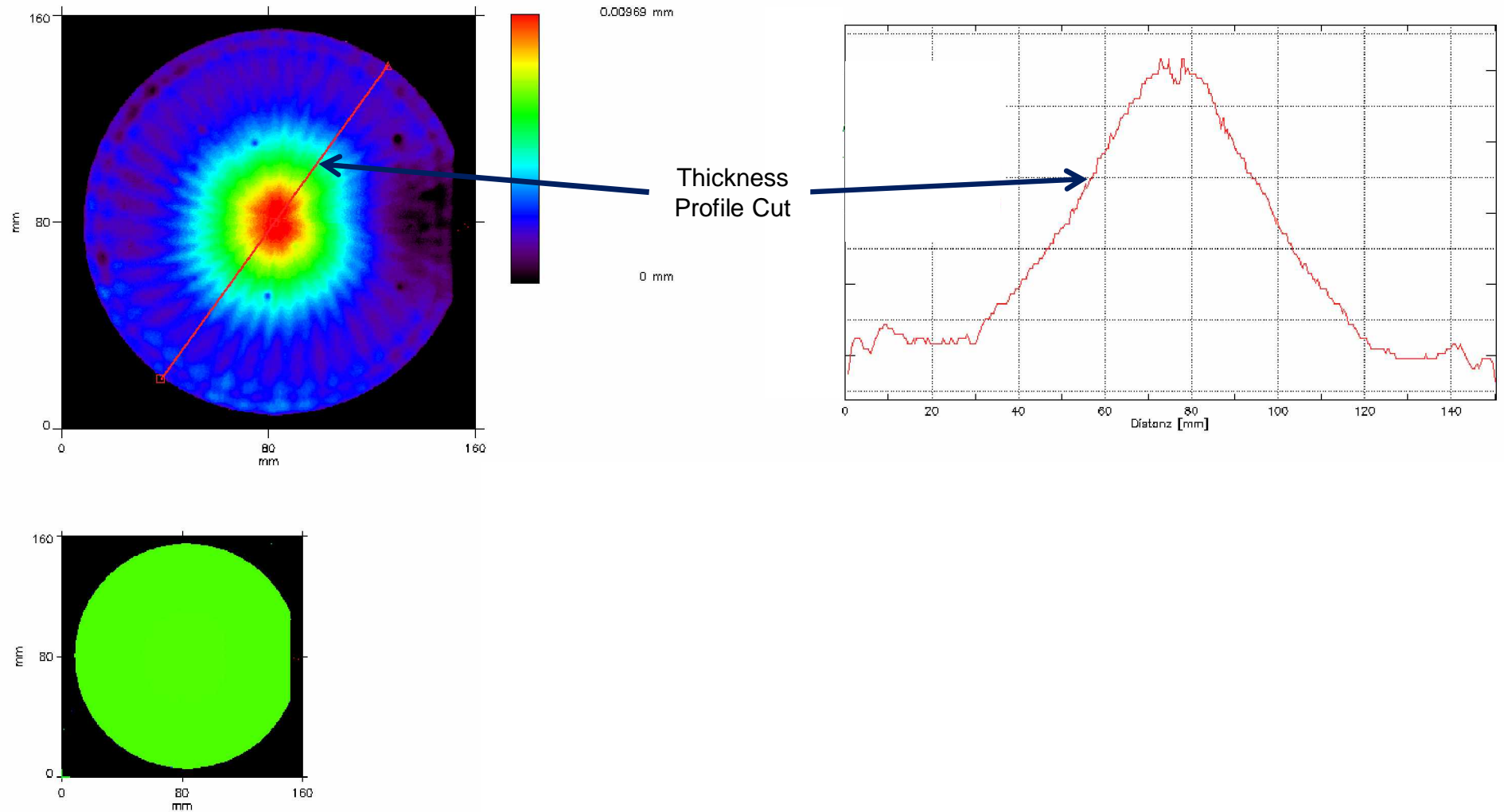


Ideas with system



Measuring Examples

CHRcodile IT: Thickness Scan of a Si-Wafer – Thickness Profile Cut

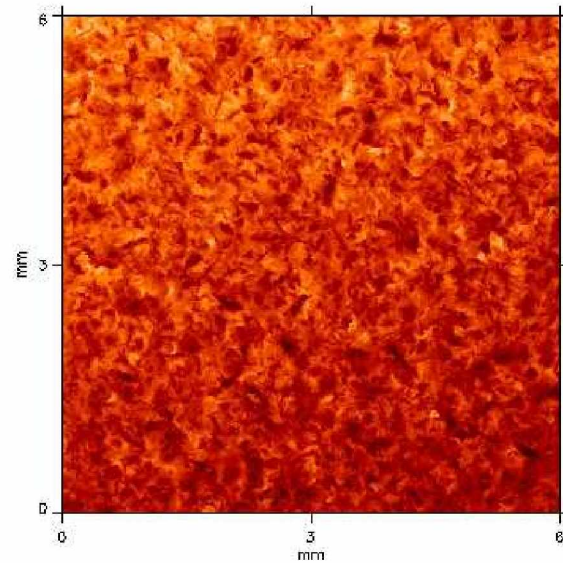


Ideas with system



Measuring Examples

CHRcodile E: Roughness Parameters of Surfaces



Filtered surface parameter

Analyze Close

Waviness Roughness

Use noise filter

0.020

Noise filter Ls [mm]

1.000

Cutoff wavelength Lc [mm]

Ignore Lc at line start and line end

Ignore Lc/2 at line start and line end

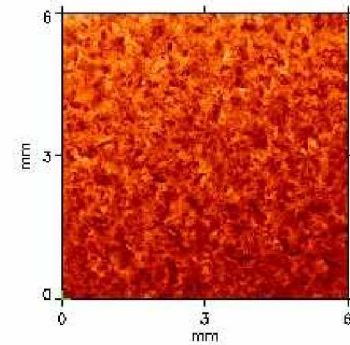
Ignore Lc at line start only

Use full evaluation length

Copy filtered data after close

Roughness filtered image

A smaller version of the surface image, framed in red, showing the result of the filtering process.



```
Statistics of roughness data (Lc = 1.000 mm) :  
sRa : 13.098 µm  
sRq : 16.520 µm  
sRz (DIM) : 145.275 µm  
sRmax : 159.119 µm  
sRp : 76.830 µm  
sRv : 93.002 µm  
sRt : 169.832 µm  
sRsk : -0.260  
sRku : 3.210  
sRk : 42.286 µm  
sRpk : 13.890 µm  
sRvk : 19.251 µm  
sMr1 : 8.352 %  
sMr2 : 89.518 %
```